

JOHNSON ET AL. — 10/621,464
Client/Matter: 071469-0304543

IN THE CLAIMS:

This listing of claims will replace all prior versions, and listings, of claims in the application:

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8/29/2006
1. (Currently Amended) A vertically translatable chuck assembly for supporting a workpiece at different locations within a plasma reactor chamber having sidewalls surrounding an interior region, comprising:
 - a chuck base having a perimeter, an upper surface and lower surface;
 - at least one support arm extending outwardly from said perimeter to said sidewalls so as to support said chuck base within said interior region;
 - a workpiece support member having a lower surface and an upper surface capable of supporting the workpiece, arranged above said chuck base upper surface;
 - a match network having at least a portion, comprising a first variable capacitor, mounted to said workpiece support member lower surface, within said chuck assembly, so as to be in direct electrical communication with said workpiece support member lower surface;
 - and
 - one or more vertical translation members arranged between and operatively connecting said chuck base and said workpiece support member for supporting and vertically translating said workpiece support member relative to said chuck base.
 2. (Original) An assembly according to claim 1, wherein one or more of said at least one support arm is adapted to provide mechanical, fluid, electrical and/or pneumatic communication from outside the plasma reactor chamber to said chuck assembly.
 3. (Canceled)
 4. (Currently Amended) An assembly according to claim 3 claim 1, wherein said match network further includes a first inductor arranged adjacent said first variable capacitor within the chuck assembly between said chuck base upper surface and said workpiece support member lower surface.